Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L14	22	("4724619" "4788994" "5421056" "5445172" "5566466" "5666985" "5715610" "5775000" "5954072").PN. OR ("6167893"). URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/01 10:08
L15	5	14 and optical	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/01 10:30
L16	178	(substrate or wafer or semiconductor or workpiece) and (engager or holder) near3 pivot\$4 and shield	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/01 10:32
L17	. 34	(substrate or wafer or semiconductor or workpiece).ti. and (engager or holder) near3 pivot\$4 and shield	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/01 10:35
L18	1032	(substrate or wafer or semiconductor or workpiece).ti. and rotat\$4 and (engager or holder or support) near3 pivot\$4	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/01 10:36
L19	542	(substrate or wafer or semiconductor or workpiece).ti. and rotat\$4 near3 (substrate or wafer or semiconductor or workpiece) and (engager or holder or support) near3 pivot\$4	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/01 13:20
L20	4	"680616".ap.	US-PGPUB; USPAT; USOCR	OR	ON	2005/09/01 13:20

	r					· · · · · · · · · · · · · · · · · · ·
S1	42	US-3727620-\$.DID. OR US-3770598-\$.DID. OR US-3772105-\$.DID. OR US-4027686-\$.DID. OR US-4092176-\$.DID. OR US-4110176-\$.DID. OR US-4113492-\$.DID. OR US-4315059-\$.DID. OR US-4336114-\$.DID. OR US-43766850R-\$.DID. OR US-43766850R-\$.DID. OR US-4405416-\$.DID. OR US-4489740-\$.DID. OR US-4510176-\$.DID. OR US-4518678-\$.DID. OR US-4519846-\$.DID. OR US-4519846-\$.DID. OR US-4732785-\$.DID. OR US-5022419-\$.DID. OR US-5039381-\$.DID. OR US-5039381-\$.DID. OR US-5055425-\$.DID. OR US-5095027-\$.DID. OR US-5154199-\$.DID. OR US-5154199-\$.DID. OR US-6167893-\$.DID. OR US-6167893-\$.DID. OR US-6217667-\$.DID. OR US-6290865-\$.DID. OR US-6290865-\$.DID. OR US-6309981-\$.DID. OR US-6319841-\$.DID. OR US-6357142-\$.DID. OR US-6416644-\$.DID. OR US-6446643-\$.DID. OR	US-PGPUB; USPAT	OR	ON	2005/08/29 15:46
		US-6446644-\$.DID. OR US-6537416-\$.DID. OR				
		US-6550484-\$.DID.				
S2	1746	134/94.1,95.1,95.2,95.3,102.1. ccls.	US-PGPUB; USPAT	OR	ON	2005/08/26 15:50
S3	495	S2 and (wafer or semiconductor or substrate)	US-PGPUB; USPAT	OR	ON	2005/08/26 15:50
S 4	298	S3 and rotat\$4	US-PGPUB; USPAT	OR	ON	2005/08/26 15:51
S5	115	S4 and (nozzle or spray or fluid) near3 (top or front or back or bottom or topside or backside)	US-PGPUB; USPAT	OR	ON	2005/08/26 15:54
S6	32	S5 and sensor	US-PGPUB; USPAT	OR	ON	2005/08/26 15:51
Sparch F	1:-1- 0/4/	2005 2:27:55 DM Dago 2				

S7	39	S4 and (nozzle or spray or fluid) near3 ((top or front or topside) and (back or bottom or backside))	US-PGPUB; USPAT	OR	ON	2005/08/26 16:44
S8	1032	134/137,140,149,151,154.ccls.	US-PGPUB; USPAT	OR	ON	2005/08/26 16:44
S9	218	S8 and (wafer or semiconductor or substrate)	US-PGPUB; USPAT	OR	ON	2005/08/29 09:54
S10	31	(wafer or semiconductor or substrate) and (mount or support) and sensor near3 optical and rotat\$4 and hub near3 (fixed or stationary)	US-PGPUB; USPAT	OR	ON	2005/08/29 12:19
S11	18	(wafer or semiconductor or substrate).ti. and (mount or support) and sensor and rotat\$4 and hub near3 (fixed or stationary)	US-PGPUB; USPAT	OR	ON	2005/08/29 13:15
S12	303	(wafer or semiconductor or substrate or workpiece) and sensor and (rotat\$4 or spin\$3 or spun) and hub near3 (fixed or stationary)	US-PGPUB; USPAT	OR	ON	2005/08/29 13:27
S13	4	"680616".ap.	US-PGPUB; USPAT	OR ,	ON	2005/08/29 16:35
S14	1352	134/149,153,157.ccls.	US-PGPUB; USPAT	OR	ON	2005/08/29 16:35
S15	490	S14 and (wafer or semiconductor or substrate or workpiece)	US-PGPUB; USPAT	OR	ON	2005/08/29 16:38
S16	466	S15 and (rotat\$4 or ((shaft or hub or rod or tube) near3 (stationary or static or fixed)))	US-PGPUB; USPAT	OR	ON	2005/08/29 16:45
S17	59	S15 and (((shaft or hub or rod or tube) near3 (stationary or static or fixed)))	US-PGPUB; USPAT	OR .	ON	2005/08/30 07:57
S18	47639	"17" and optical near3 sensor	US-PGPUB; USPAT	OR	ON	2005/08/30 07:57
S19	1352	134/149,153,157.ccls.	US-PGPUB; USPAT	OR	ON	2005/08/30 07:57
S20	490	S19 and (wafer or semiconductor or substrate or workpiece)	US-PGPUB; USPAT	OR	ON	2005/08/30 07:57
S21	59	S20 and (((shaft or hub or rod or tube) near3 (stationary or static or fixed)))	US-PGPUB; USPAT	OR	ON.	2005/08/30 07:57
S22	9	S21 and optical near3 sensor	US-PGPUB; USPAT	OR	ON	2005/08/30 07:57

S23	8717	(wafer or semiconductor or substrate or workpiece) and (nozzle or spray or fluid) and rotat\$4	EPO; JPO; DERWENT	OR	ON	2005/08/30 08:44
S24	136	S23 and (shaft or hub or rod or tube) near3 (stationary or static or fixed)	EPO; JPO; DERWENT	OR	ON	2005/08/30 08:45
S25	60	"5375291"	US-PGPUB; USPAT	OR	ON	2005/08/31 14:56
S26	1352	134/149,153,157.ccls.	US-PGPUB; USPAT	OR	ON	2005/08/31 16:09
S27	490	S26 and (wafer or semiconductor or substrate or workpiece)	US-PGPUB; USPAT	OR	ON	2005/08/31 16:09
S28	59	S27 and (((shaft or hub or rod or tube) near3 (stationary or static or fixed)))	US-PGPUB; USPAT	OR	ON	2005/08/31 16:10
S29	42	Donoso.in.	US-PGPUB; USPAT	OR	ON	2005/08/31 16:10